



# COHERENT<sup>®</sup>

## *High Power CW and QCW Diode Monolithic Stack Technology Overview*

*Mark Mondry*



# Outline

- **Bar Technology**

- 808 nm AAA™ “Extended Power” Bars
- 9xx nm High Efficiency Bars

- **Stack Technology**

- Conductively Cooled “G-stack” – Gen 4
- Silicon Monolithic Microchannels (SiMMs)

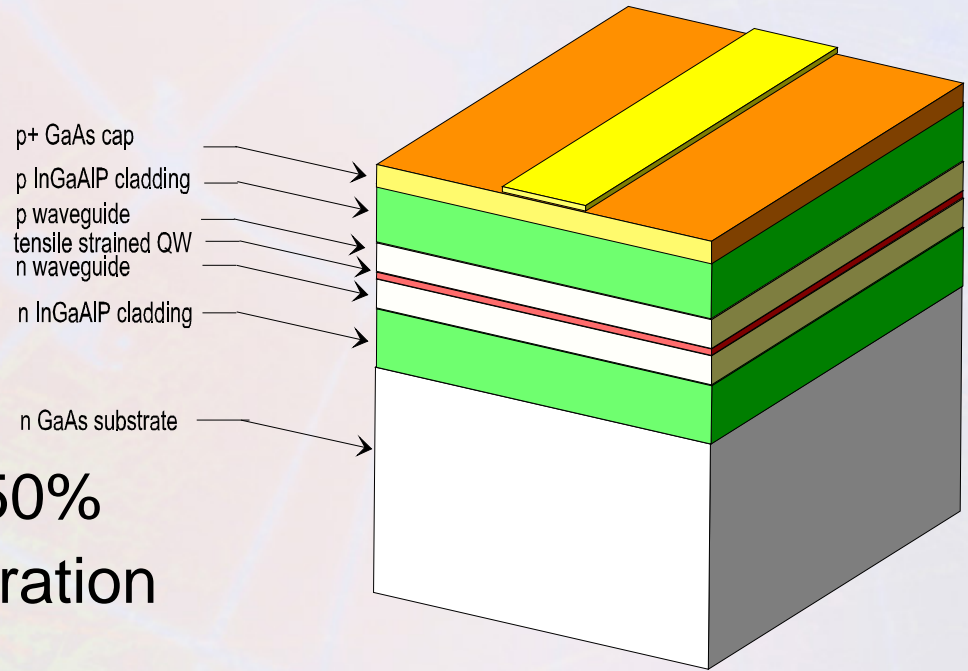
- **On The Horizon**

# Bar Technology 808 nm AAA™ “Extended Power” Bars





# Aluminum-free Active Area – The AAA™ Advantage



## •High Performance

- Conversion efficiencies >50%
- Elevated temperature operation

• **MBE Grown**

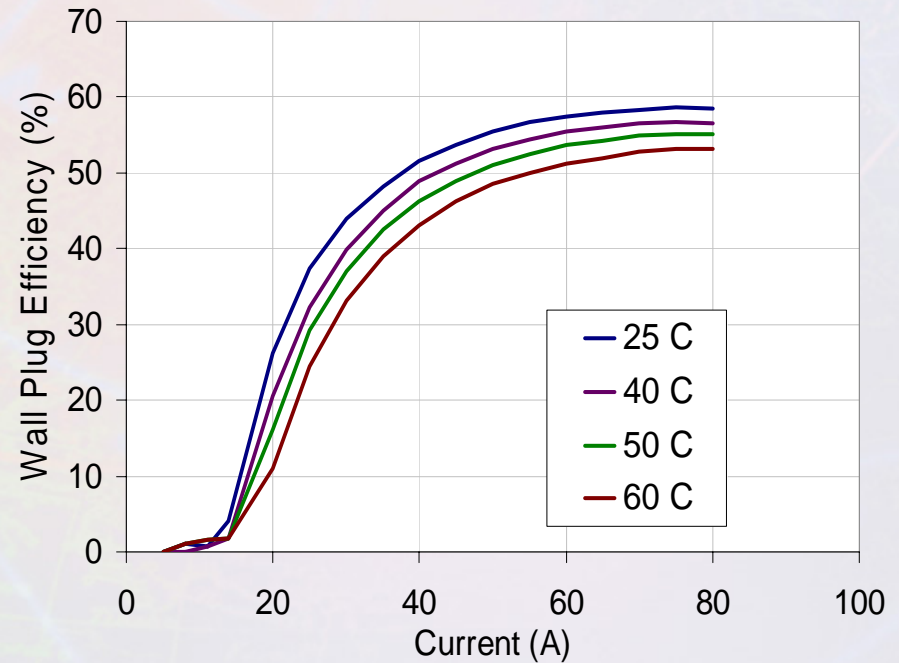
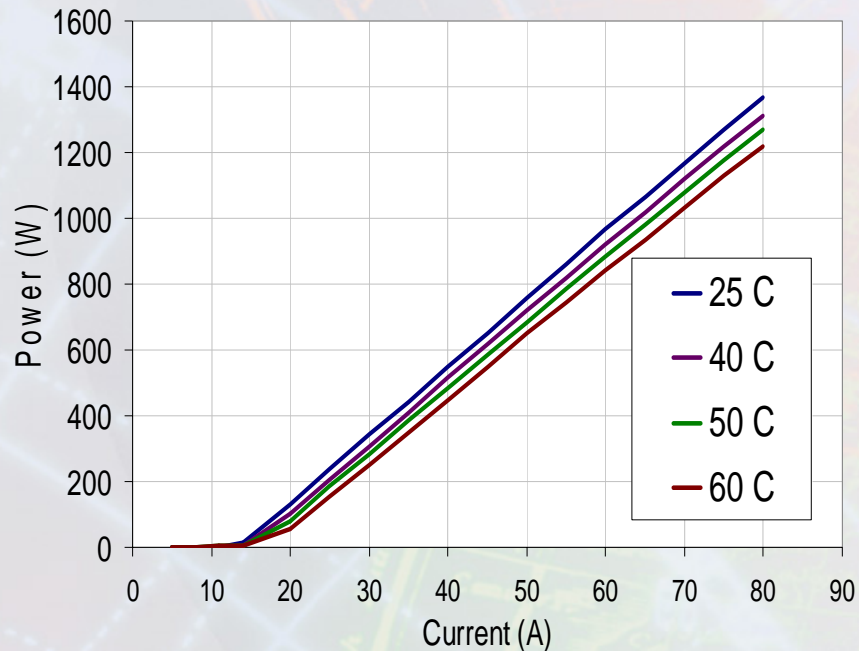
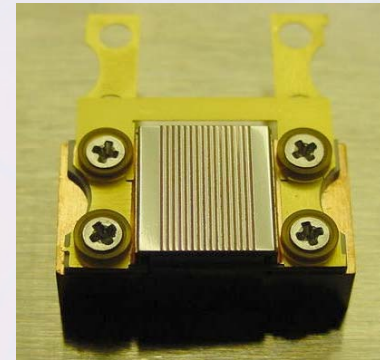
- High degree of uniformity and reproducibility

## •Intrinsic Long Lifetime

- Aluminum-free region eliminates failure mechanisms associated with AlGaAs lasers.

# High Temperature Performance

**Conductive-cooled 16 bar “G-stacks”  
250  $\mu$ sec pulses @ 0.5% duty cycle**



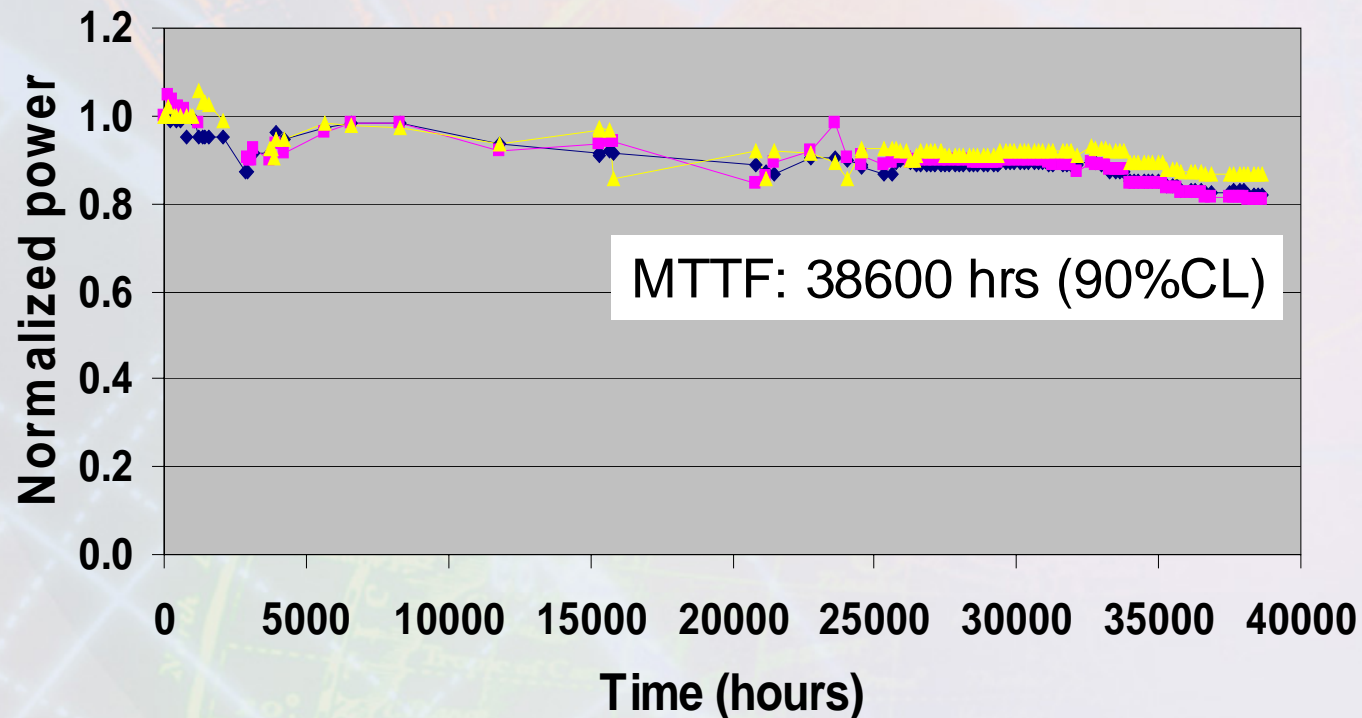
**Wall Plug Efficiency @ 808 nm >50% @ 60° C**

# Aluminum-free Active Area (AAA™) Reliability

90% FF 0.6 mm cavity on conductively-cooled package

80 Amps Constant Current (80 W) at 25° C

200  $\mu$ sec pulses @ 25% duty cycle



# Limitations of Traditional Epi Design

- Define device operating power in terms of linear power density:

$$\text{LPD} = \frac{P_{\text{op}}}{\text{width of active region}}$$

- We observe limited reliability for  $\text{LPD} \approx 20 \text{ mW}/\mu\text{m}$  for our traditional design

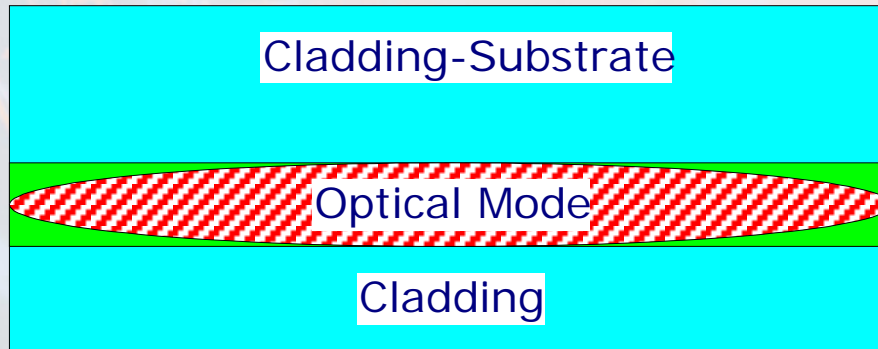
- Challenge:

How to increase the reliable operating power density while maintaining the high confidence of product consistency?



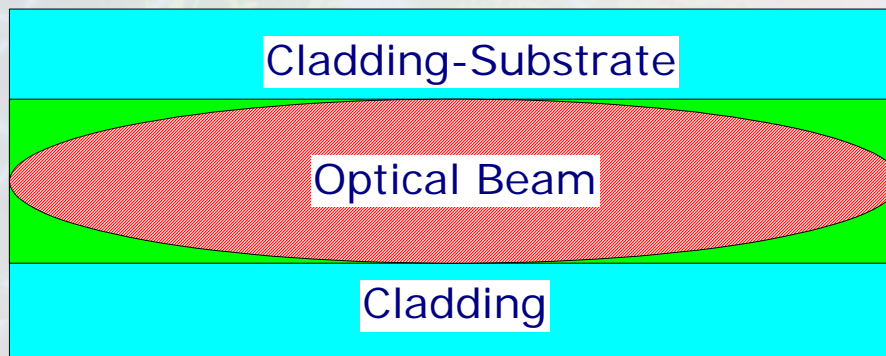
# Answer: A vertical scaling of the epitaxial structure

## Traditional Design



**Traditional waveguide designed to support single transverse mode**

## "Extended Power" Design



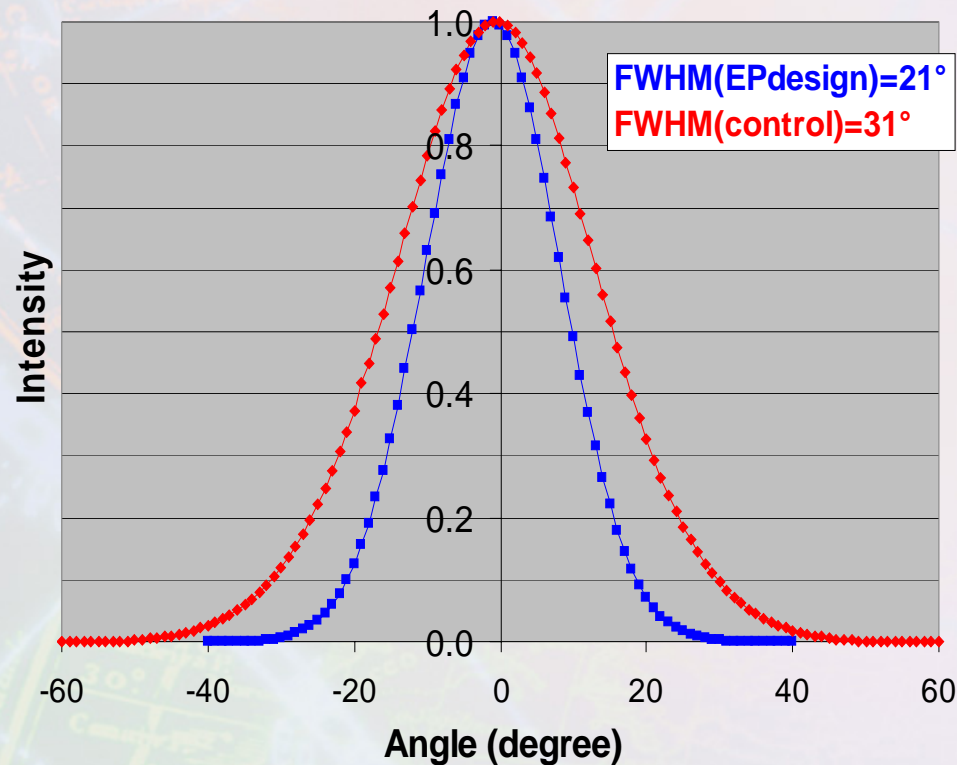
**EP design increases the waveguide thickness and expands the optical mode**



# Benefits of “Extended Power” Epi Design

- **No new processing – minimizes fabrication complexity and new failure mechanisms**
- **Increases Catastrophic Optical Damage (COD) Limit**
- **Lower Cavity Photon Density**
- **Extends the Reliable Operating Power Limit of our AAA<sup>TM</sup> technology**
- **Improved Output Beam Characteristic (fast axis)**

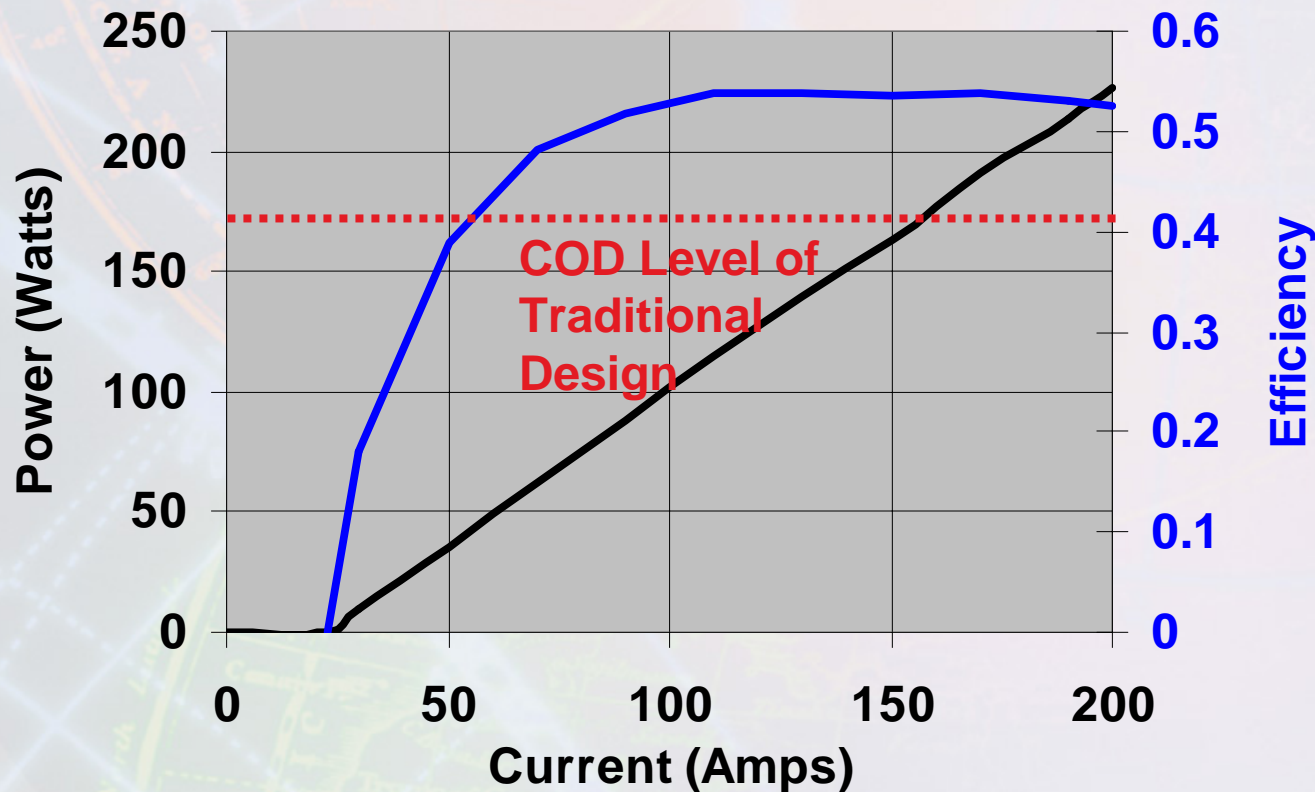
# Reduced Fast Axis Divergence – EP Design



➤ Reduced divergence enables lower cost lensing and potentially improves power coupling

# QCW Device Performance

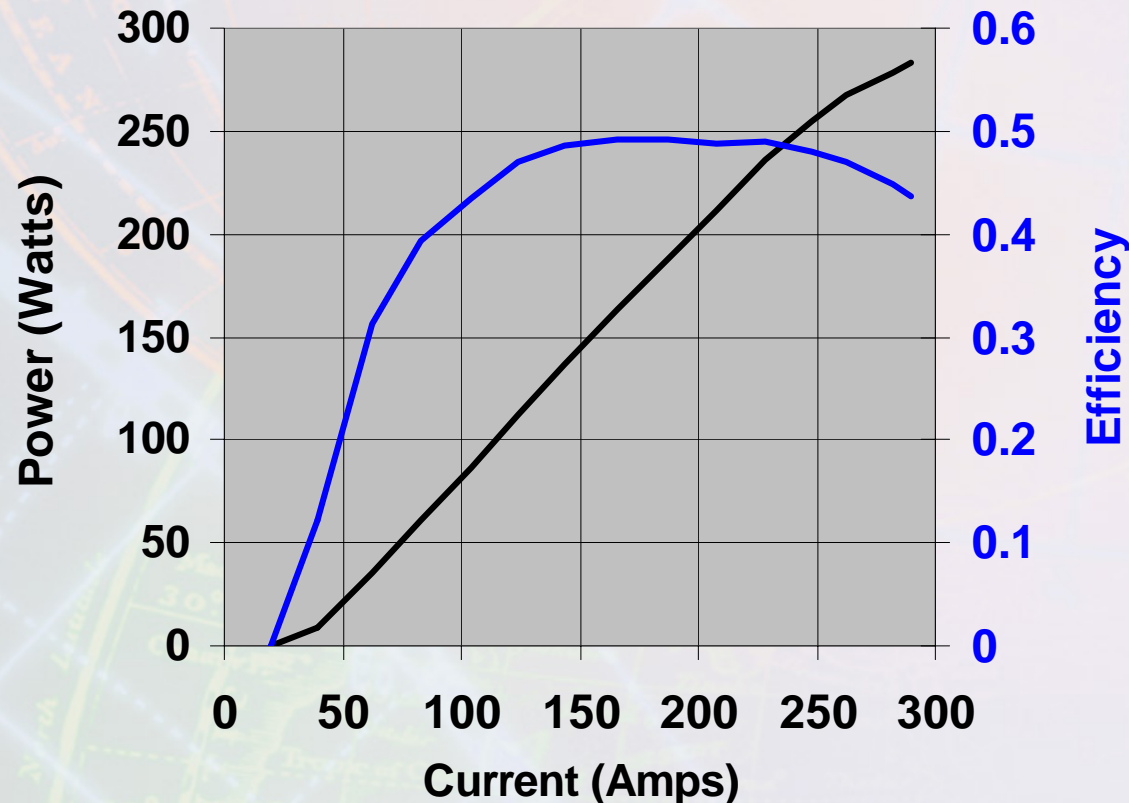
90% FF 1.0 mm cavity length tested on conductively cooled package with 200us pulse @ 100Hz at 20° C



➤ WPE is 53% @  $P_{op}=200$  Watt

# QCW Device Performance

90% FF 1.5 mm cavity length tested on conductively cooled package with 500us pulse @ 50Hz at 25 ° C

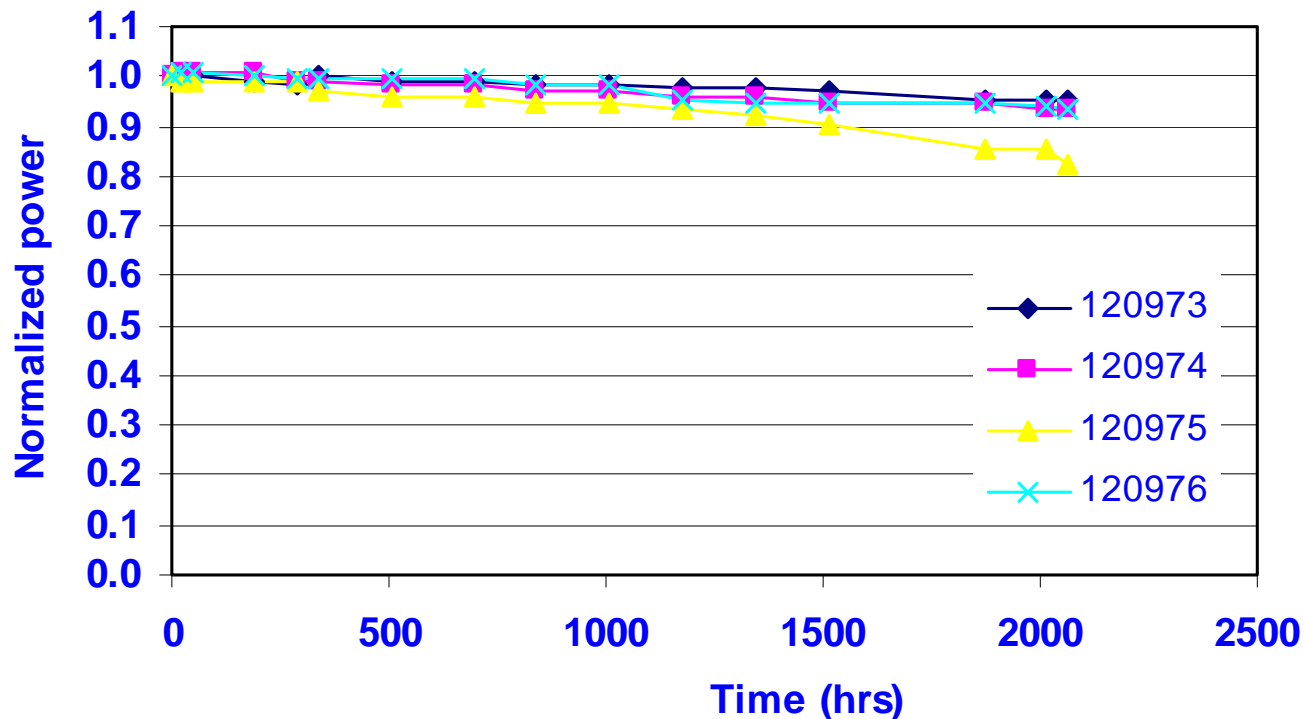


➤ **270 watts with an efficiency of 45%**



# QCW Device Reliability

“Half bar” 90% FF 1.5 mm cavity length devices tested at 150 A on conductively cooled package with 500us pulse @ 200Hz at 25° C



➤ At 270 W/cm, MTTF:4271hrs or 3.2e9 shots (90%CL)

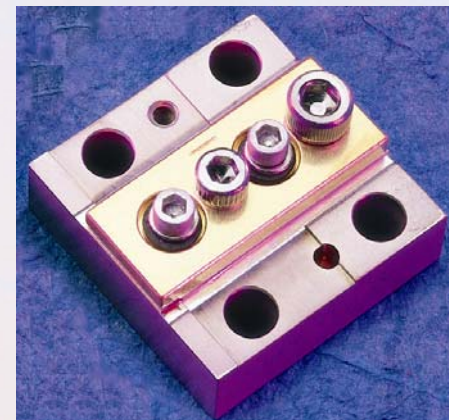
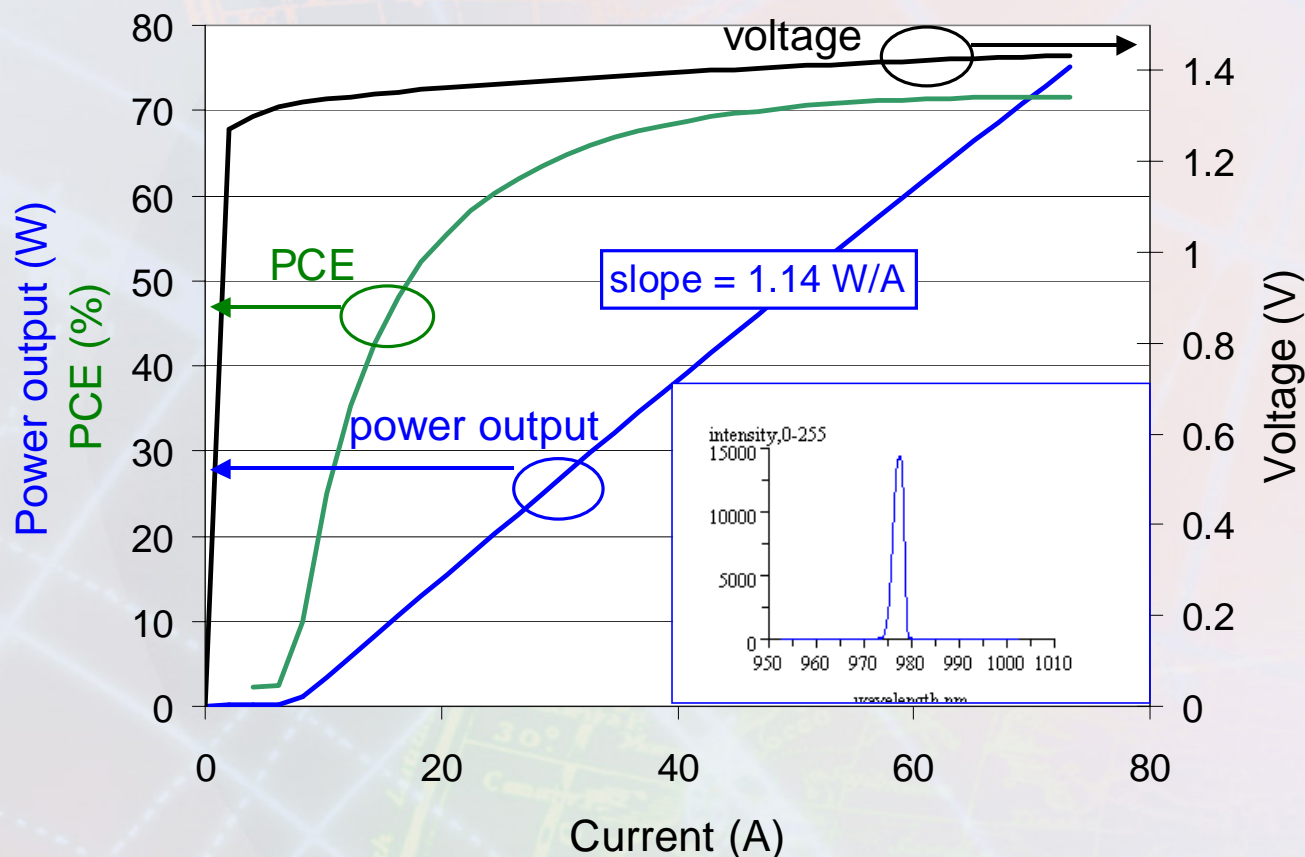
# Bar Technology 9xx nm High Efficiency Bars



## Coherent 9xx nm Bar Technology

- **New semiconductor material system for Coherent**
  - more optimized for 9xx nm than our AAA™ material
- **Development started in early 2004**
  - First report of >60% wall plug
- **Emphasis has been on manufacturability rather than “hero” results**

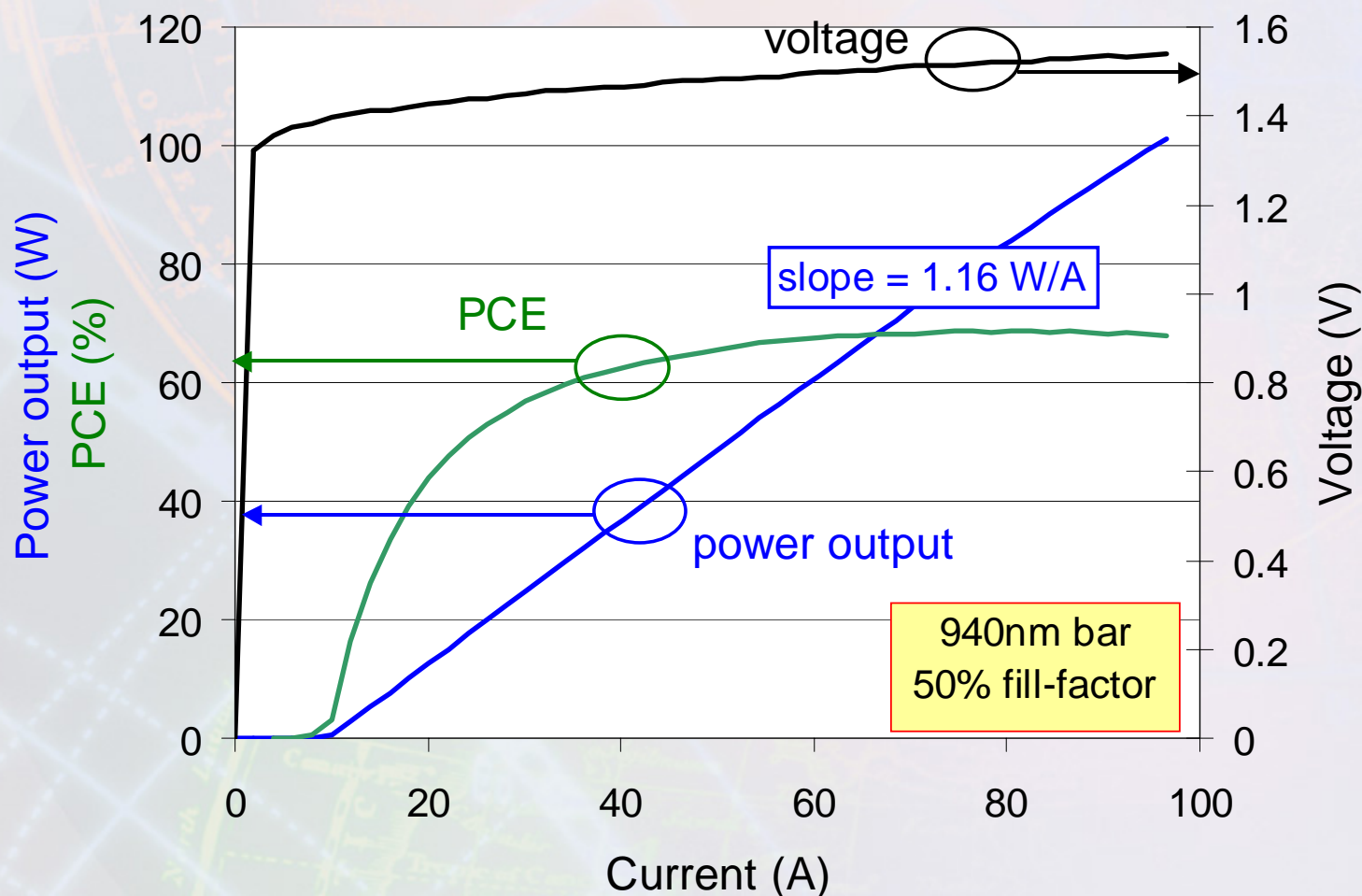
# Efficiency of our 9xx nm **conductively-cooled** bars



**71.5%** power-conversion-efficiency at 70 watts CW  
for 30% FF 1.5 mm cavity length bar



# Efficiency of our 9xx nm **conductively-cooled** bars



**50% 940 nm bars exhibit 68.2% efficiency at 100 W CW**

# Performance Comparison of Coherent bars versus SHEDS program

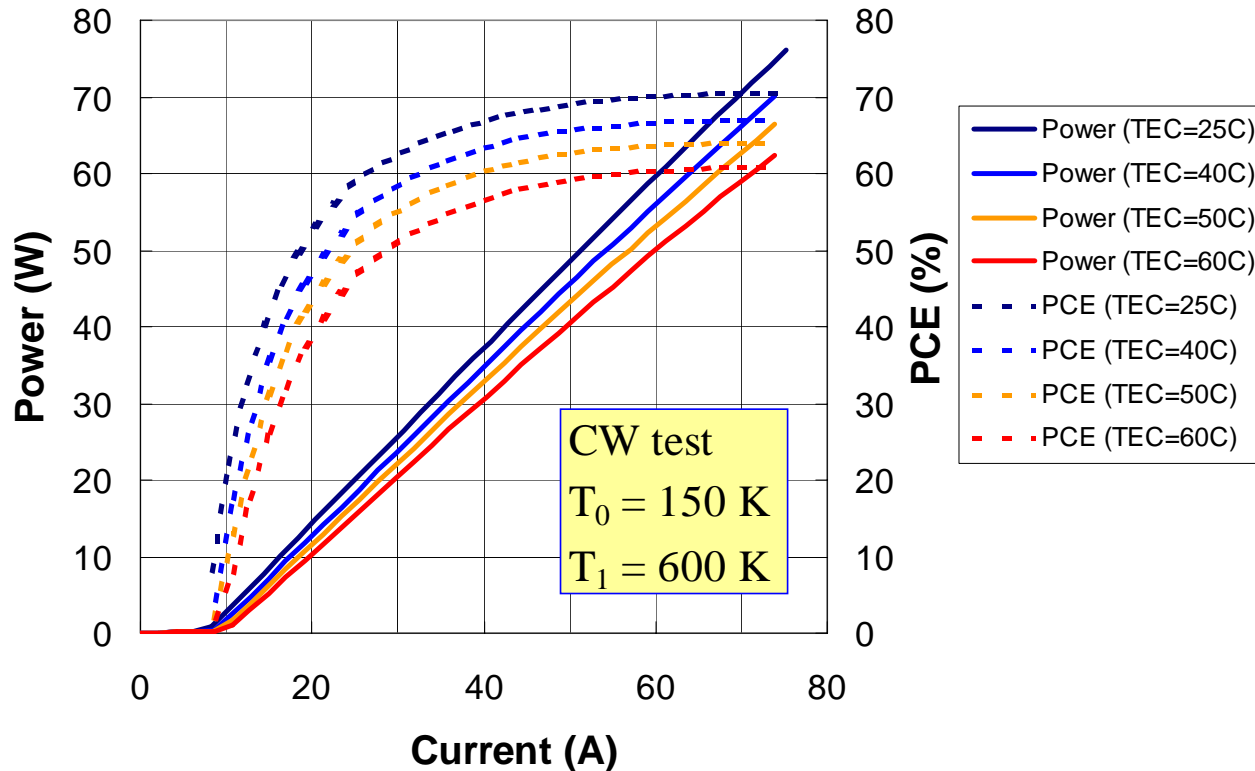
Attribute	JDSU	nLight Photonics	Alphalight	Coherent
Bar Power Output	87.9 W	89.6 W	81.4W	75 W with 30% FF bars; 100 W with 50% FF bars
Cool Type	Active water cooling	Active water cooling	Active water cooling	Passive conduction cooling
Bar Power Conversion Efficiency	65.3%	64.1%	64.7%	71.5% at 75W; 68.2% at 100W
Reliability at this power & geometry	unknown	unknown	unknown	MTTF > 20,000 hours for 75W bars. Reliability test in progress for 100W bars
Junction Temperature	50.7°C	49.5°C	51.1°C	40°C at 75 W; 50.5°C at 100 W
Spectral Width	3.8 nm	0.8 nm	3.5 nm	3.5 nm

# “Real World” Efficiencies of 9xx nm CCP products in manufacturing

Test Condition: (CW @ TEC = 25 °C, passively cooled)	Highest CCP PCE	Typical CCP PCE tested in factory
980 nm	71.5%	66%
940 nm	69.5%	65%
915 nm	67.0%	64%

# Efficiency of our 9xx nm bars at elevated temperatures

Temperature performance of Coherent passively-cooled 980 nm bars



□ High-temp epi-design

□ 30% fill-factor bar

□ PCE > 60% @

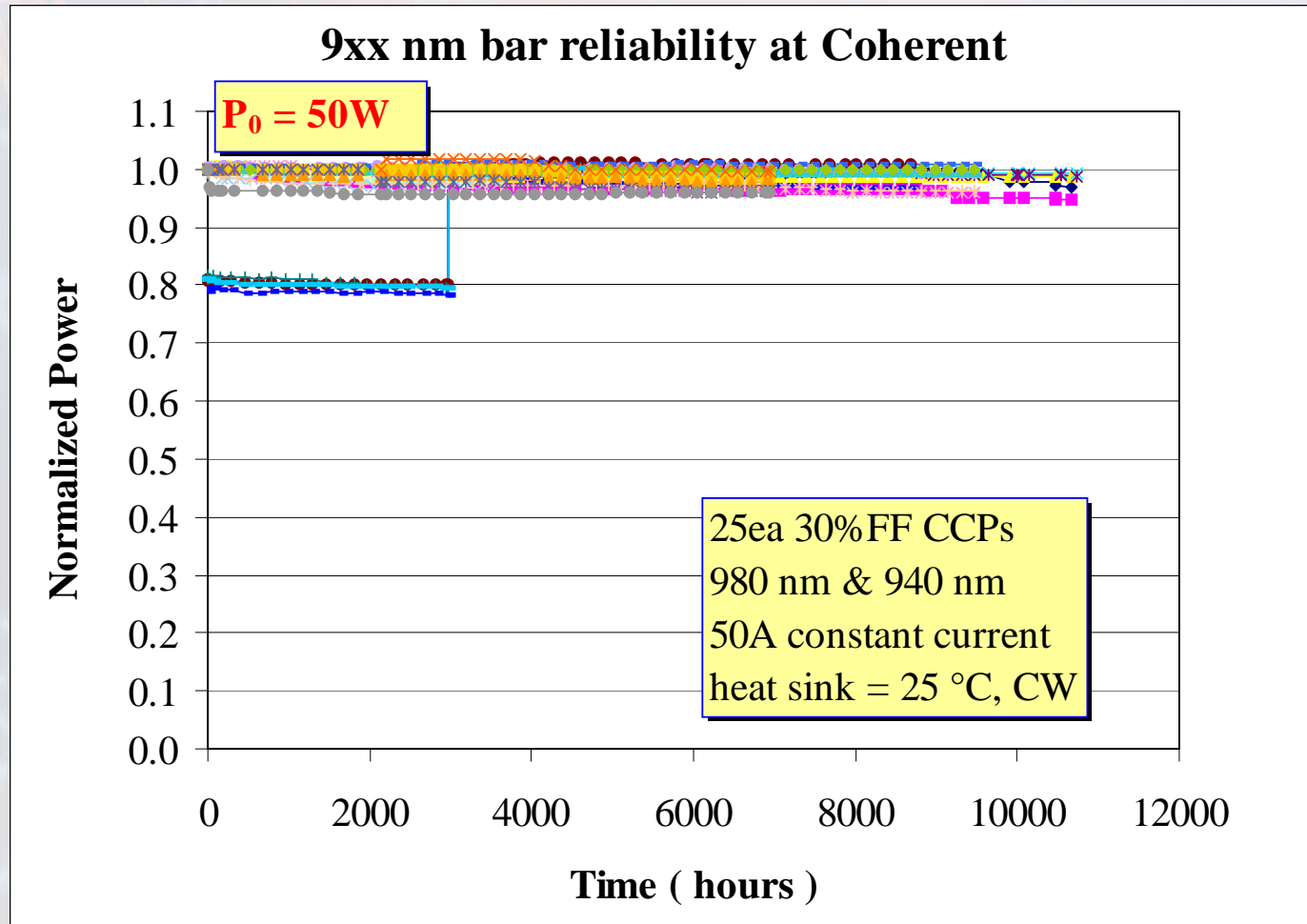
➤ TEC = 60°C

➤ 60W CW

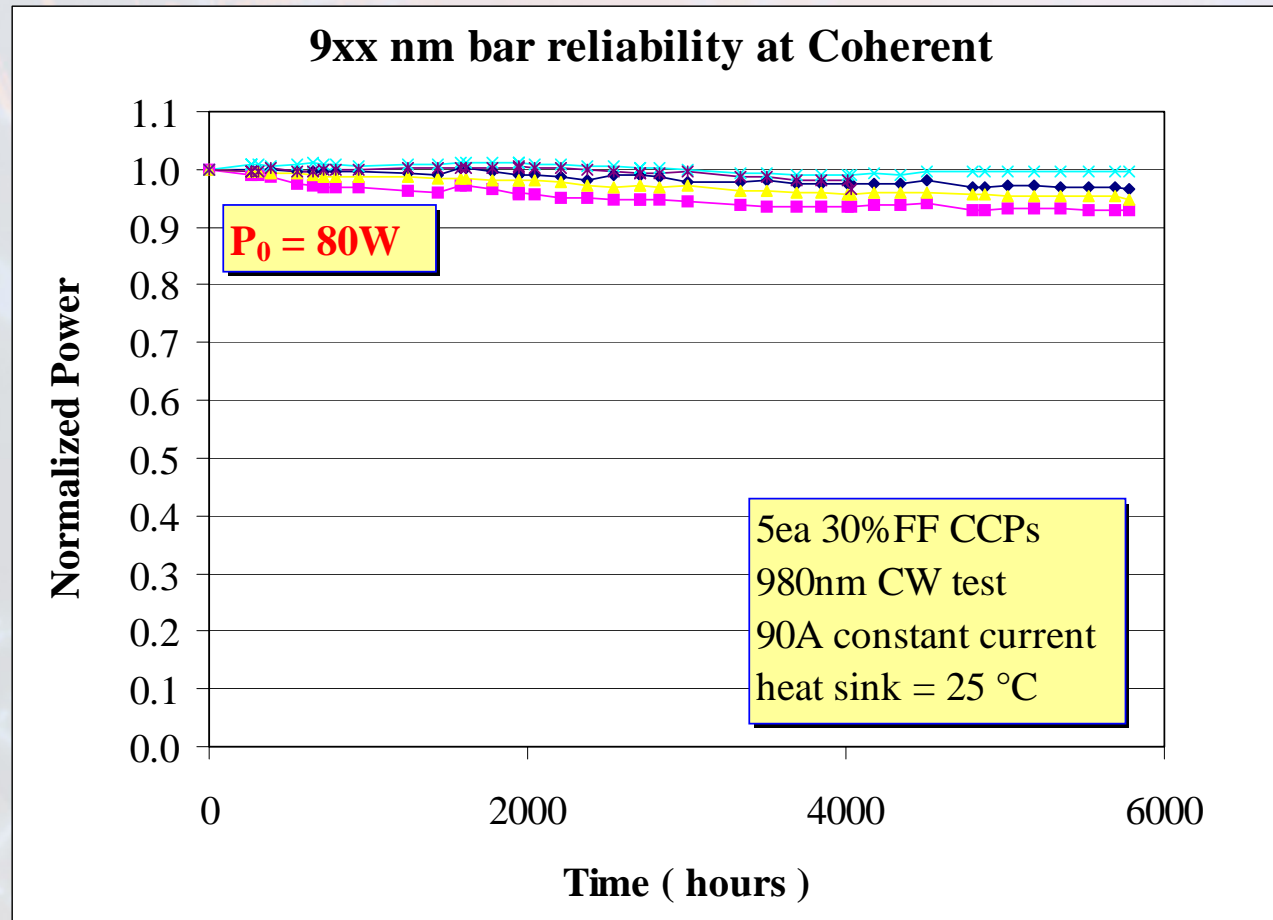
➤ Passively cooled



# Reliability of our 9xx nm bars at 50W



# Reliability of our 9xx nm bars at 80W



# Reliability Summary of our 9xx nm Bars

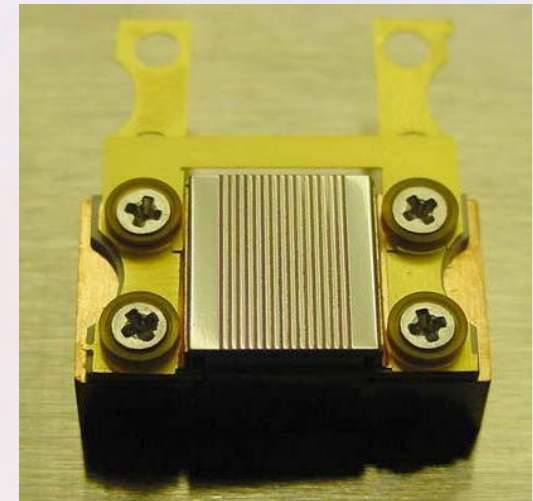
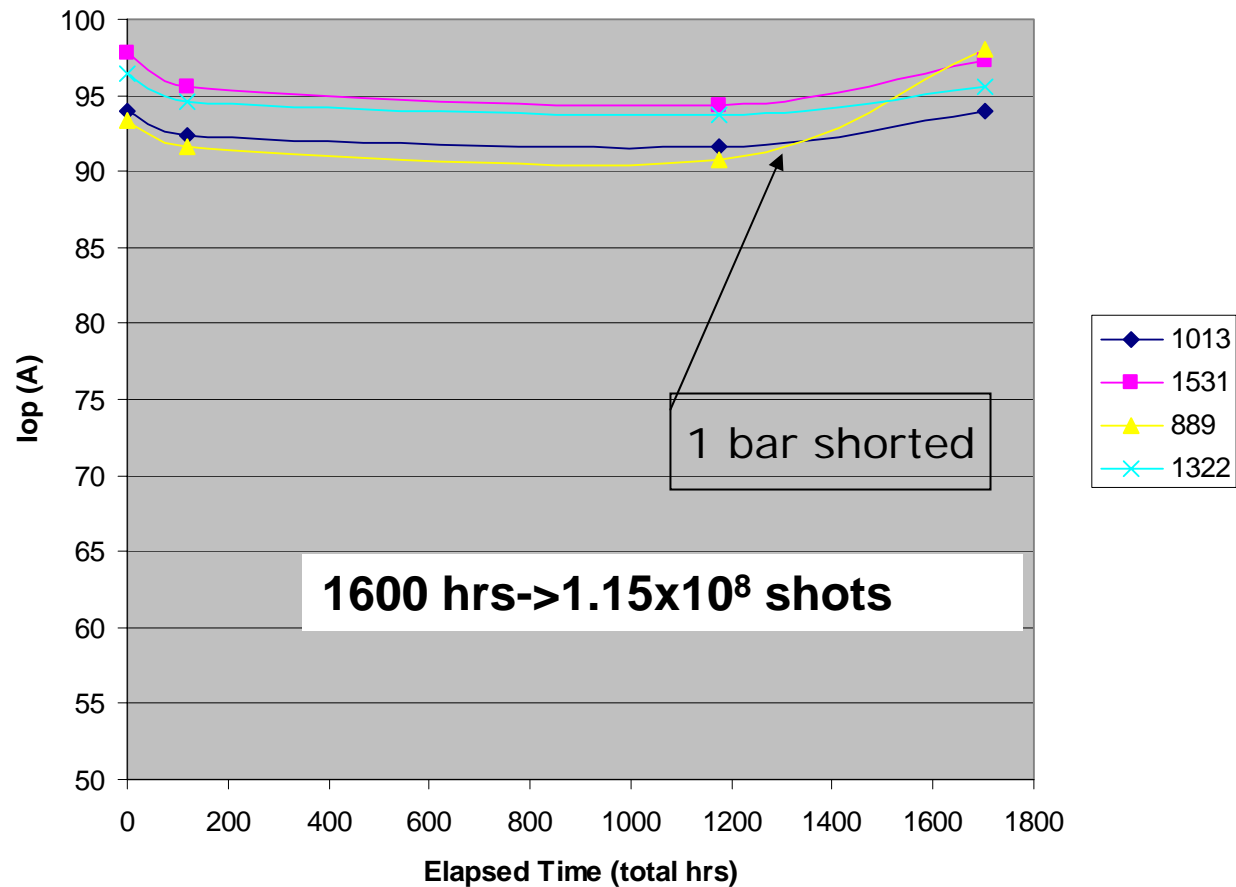
- ❑ 83 **30% fill-factor** CCPs have been lifetested
- ❑ power: 50-90W CW
- ❑ collected > **396,000** device hours.
  
- ❑ random failures:
  - calculated failure rate < 0.5% per kilo-hours
  - 90% confidence level for 30 %FF bars @ 50W
  
- ❑ wear-out failures:
  - Median life > 30,000 hrs (with 90% CL) at 50W CW
  - Median life > 20,000 hrs at 80W CW

# Stack Technology Conductively Cooled “G-stack” – Gen 4

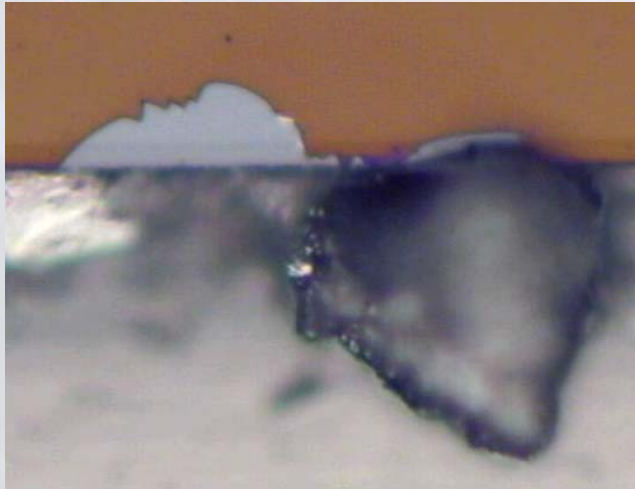




# Background: Gen III G-16 Stack Lifetest at 50 °C



## Solder Balls/Shunts

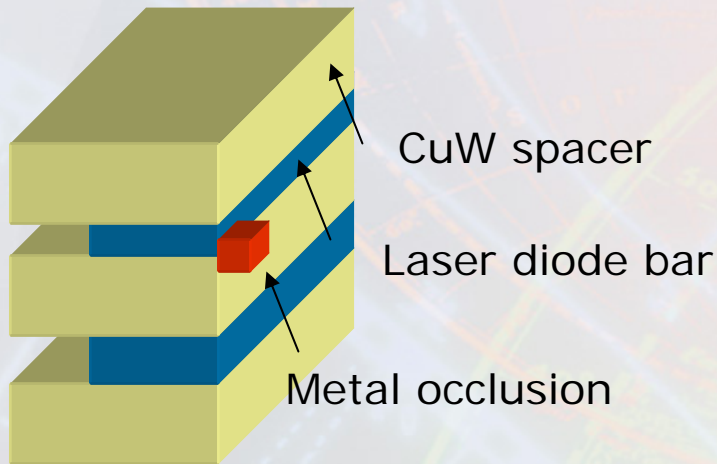


**Solder ball at peel  
site**



**Solder shunts**

# Heating Model of a Metal Occlusion



Stack Crossection

Net temperature rise

heat sink temp: 50.0°C

$\Delta t_{\text{heat sink} \rightarrow \text{sub mount}}$ : 6.8°C

peak solder temp rise: 130.1°C

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**186.9°C**

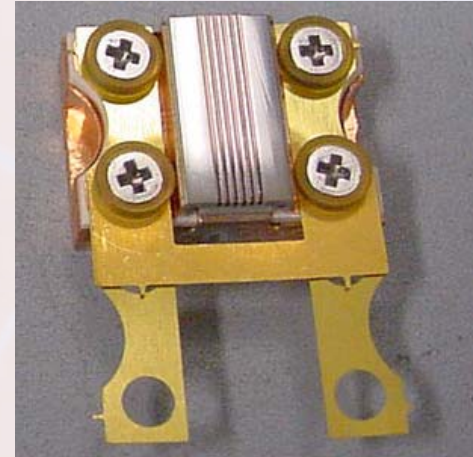
**Exceeds In-based solder reflow temperature**



# Gen 4 G-stack Development

## Advantages of Hard Solder

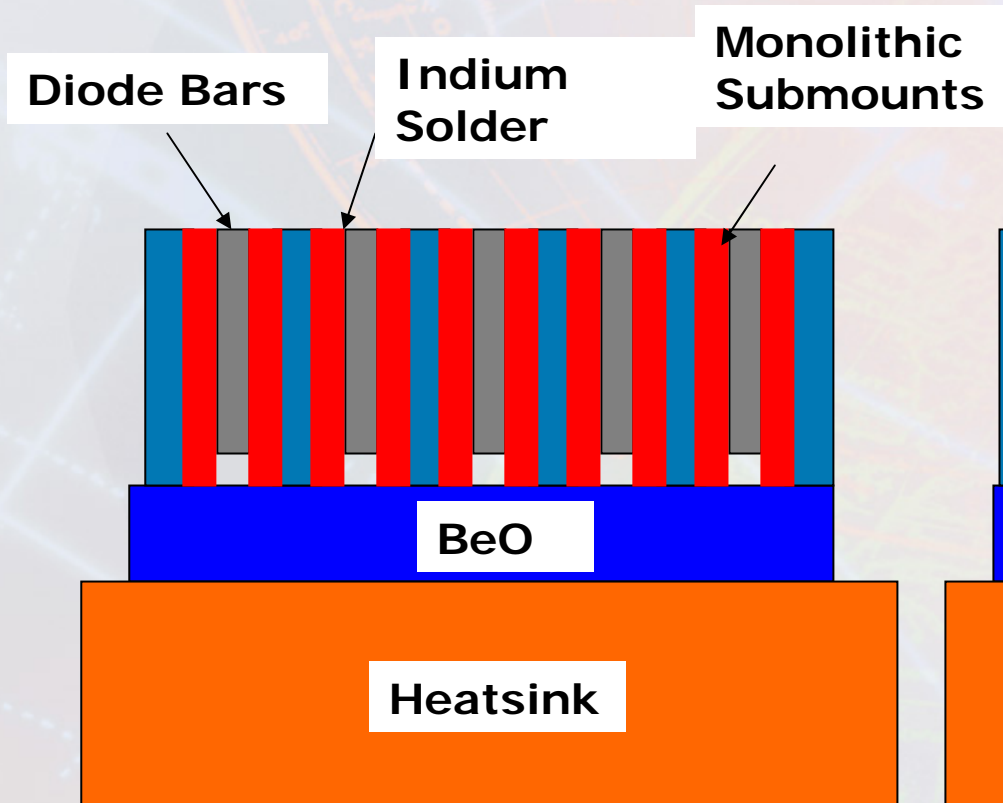
- Improves device yield
  - due to increased process window
- Improves bar to bar registration
  - consistent p-side solder volume
  - Repeatable bar preloading technique
  - Computer controlled time/temp profiles for reflow.
- Expected substantial lifetime improvement
  - substantial temperature “headroom” on p-side solder joint
  - Stable phase solder with Telecom proven reliability



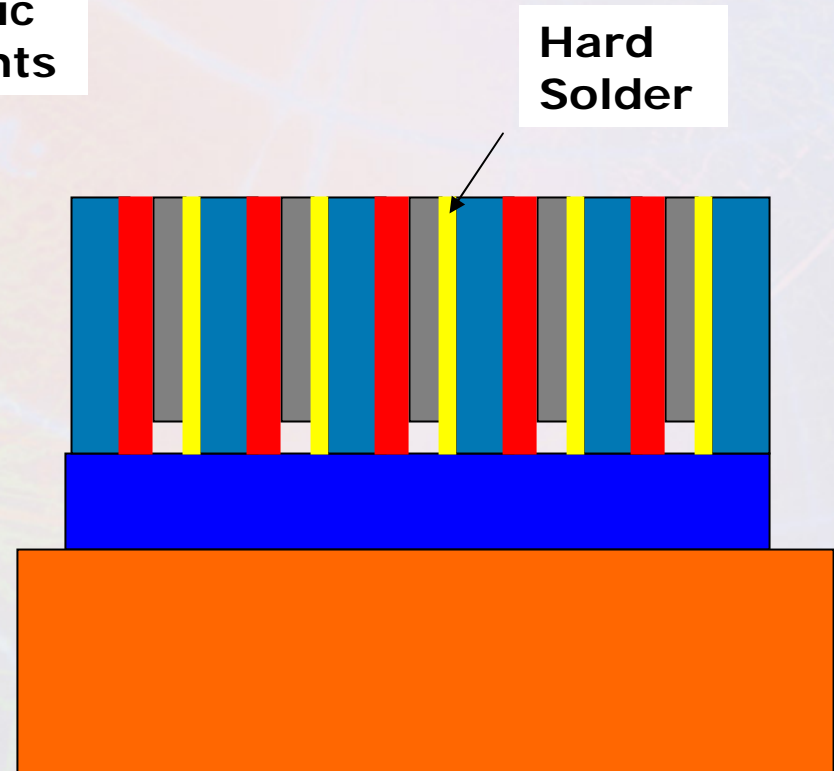


# Stack Assembly Methods

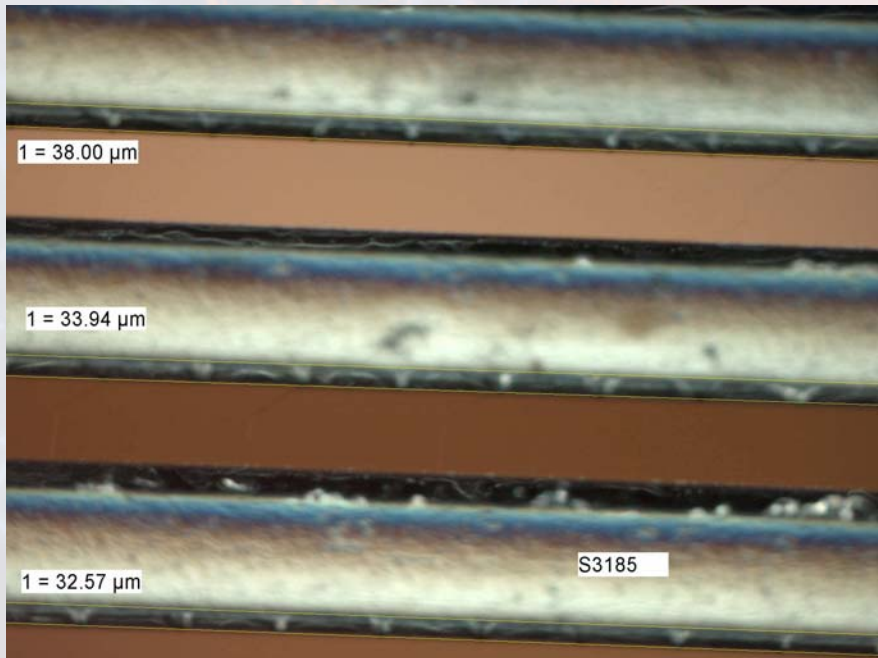
## Gen III G-Stack



## Gen 4 G-Stack

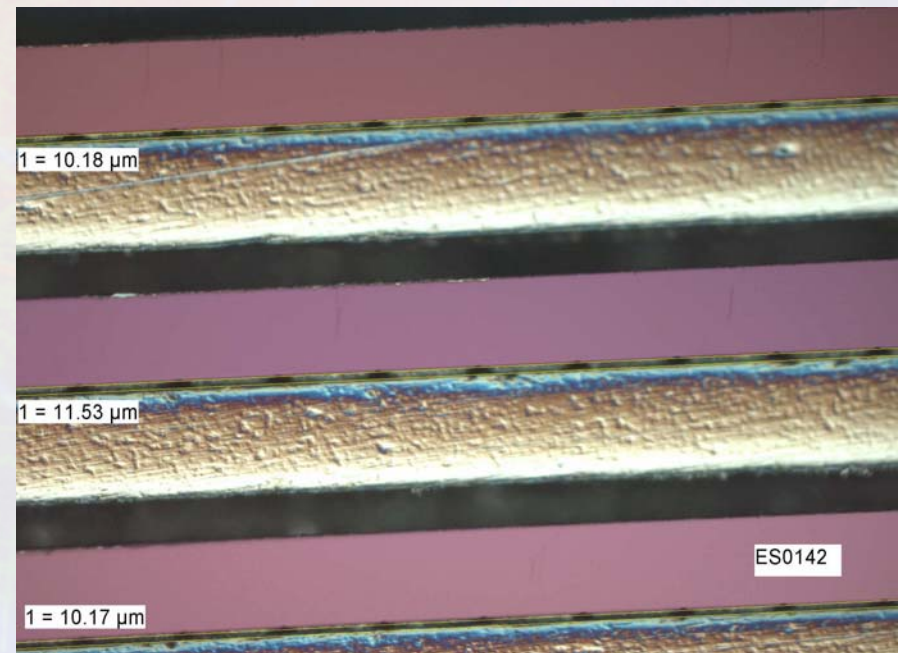


# P-side solder junction thickness

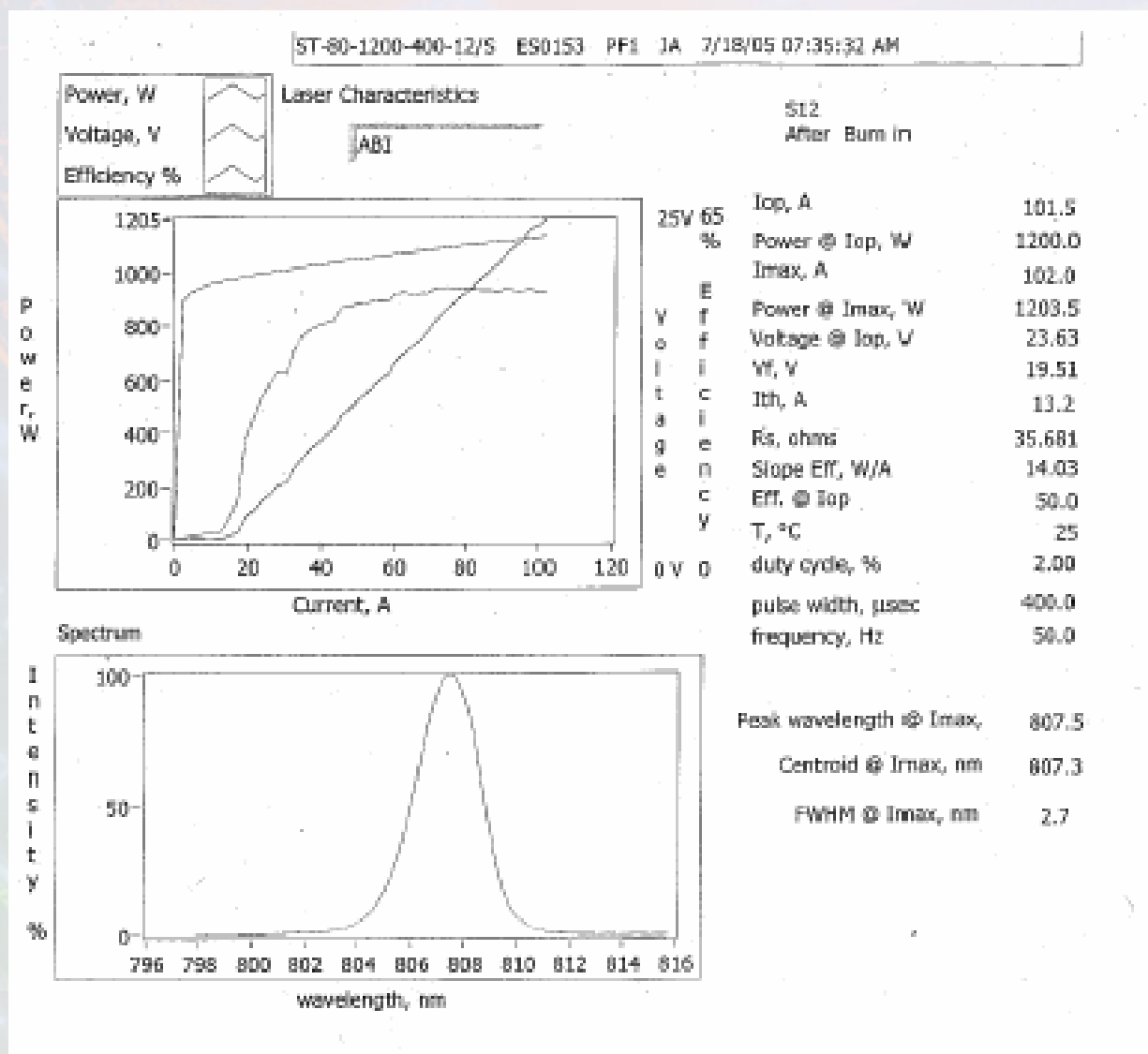


Soft Solder p-side

Hard solder p-side

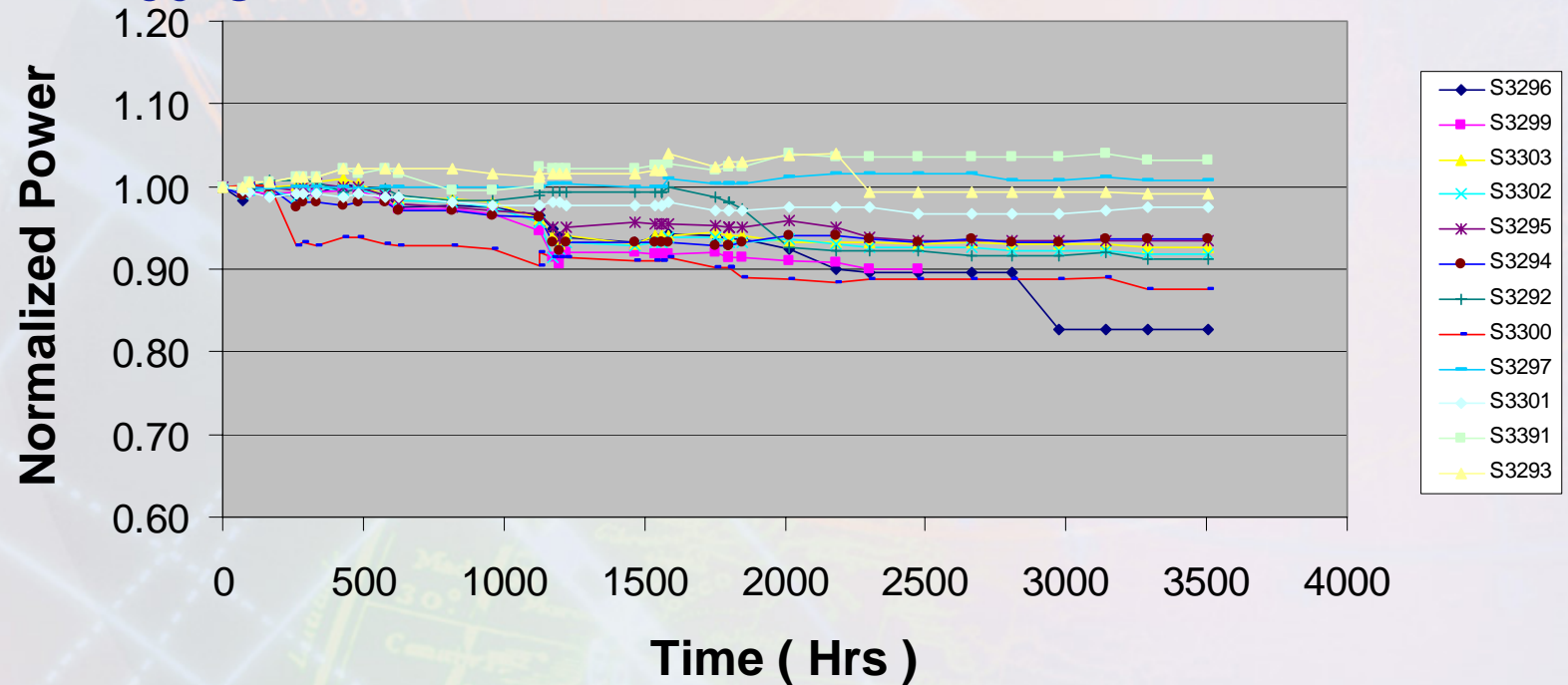


# Typical Stack PIV Spectrum



# Hard Solder Stack Reliability

16 Bar Stack; 188 $\mu$ s @ 20Hz and 100Hz @ 91A,  
50 °C



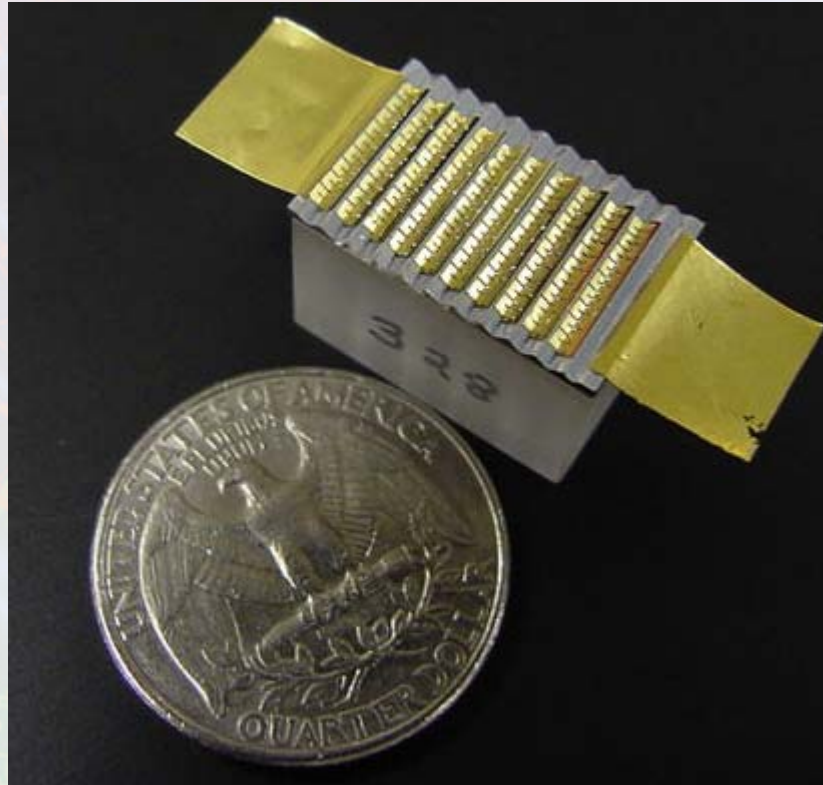
➤ **MTTF: 4.8e9 shots (90%CL)**



# Stack Technology Silicon Monolithic Microchannels (SiMMs)

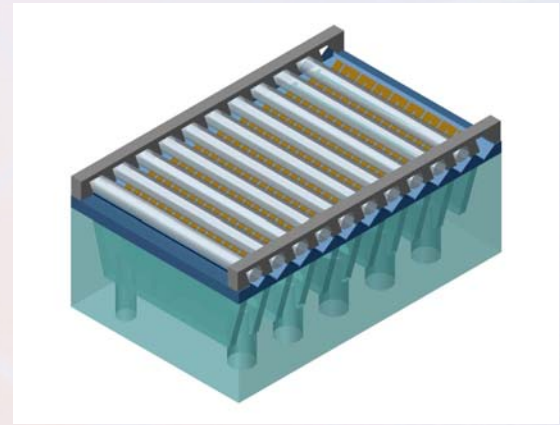


# Status of Silicon Monolithic Microchannels (SiMMs)



- Technology transfer from Lawrence Livermore National Laboratories
- Sampling by August 2006

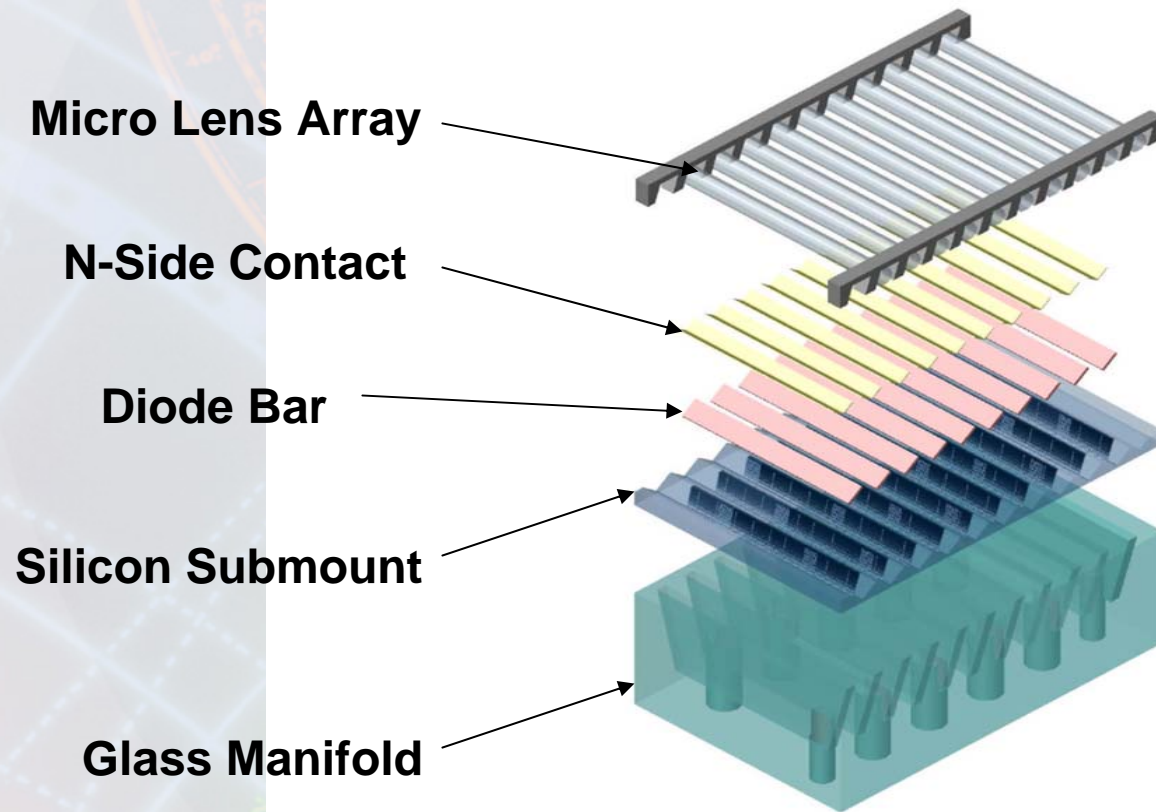
## What is “SiMMs”?



- **Vertical Water Cooled Monolithic Stack**
- **Made from Silicon V-Groove/microchannel submount bonded Pyrex manifold (no copper)**
- **Optical Power-1000-1500W CW  $\longrightarrow$  2000W QCW**
- **Lensable with Fast Axis lens array**
- **Low Thermal Impedance- 0.35 deg.C/W/bar**

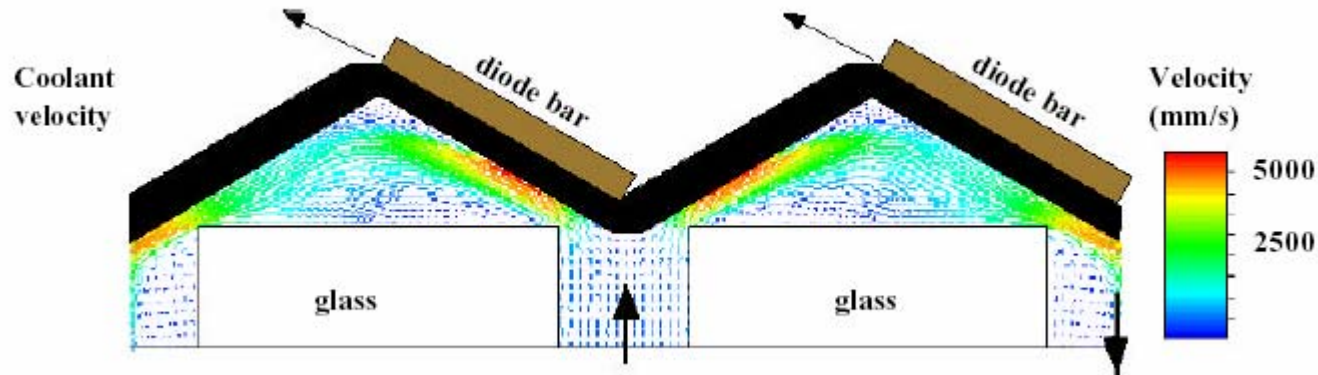


# SiMMs Anatomy

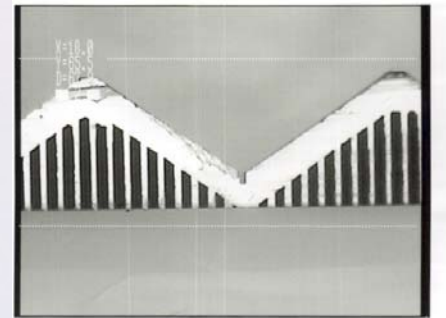
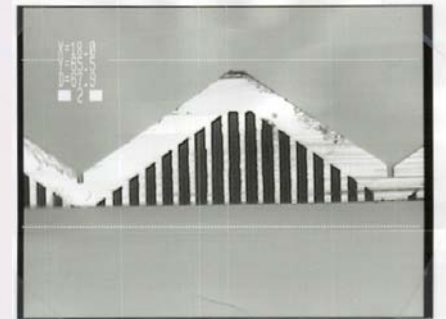




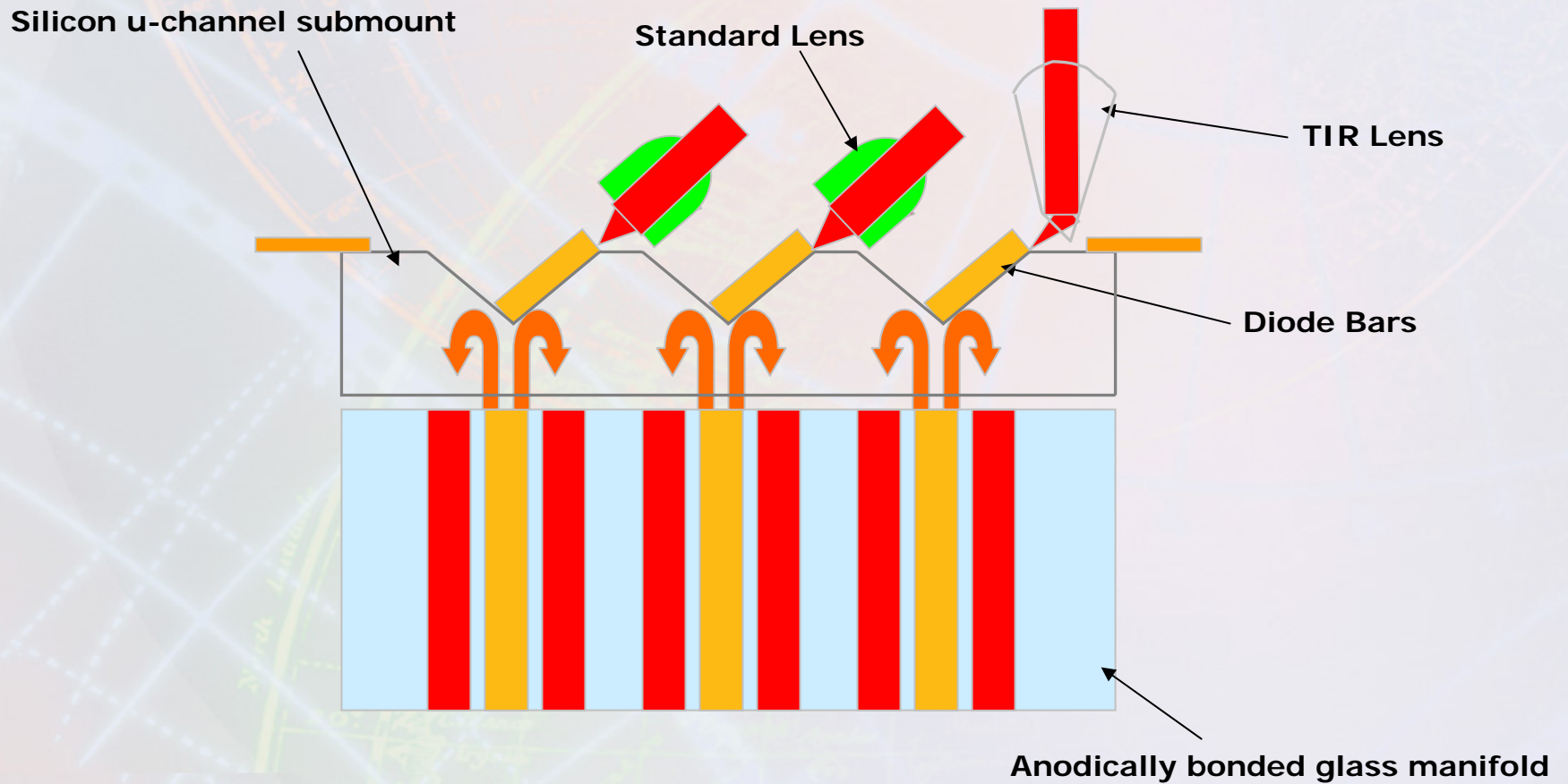
## SiMMs Water Flow



Submount Cut-Away



# SiMMs Stack

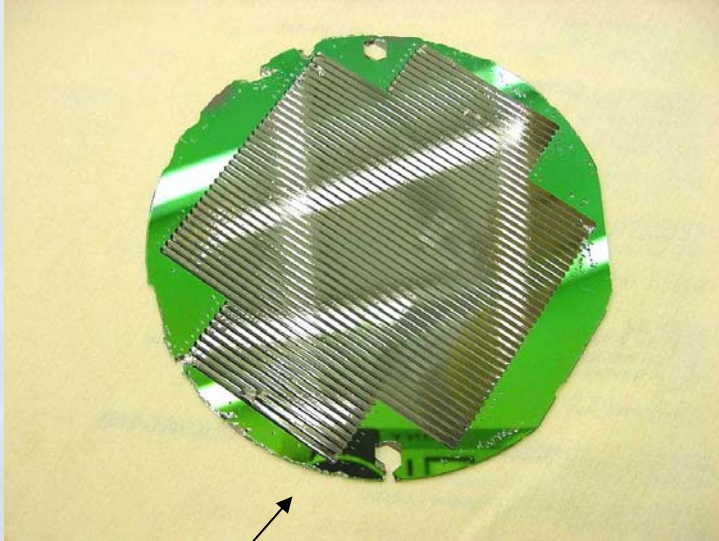


# Advantages of SiMMs

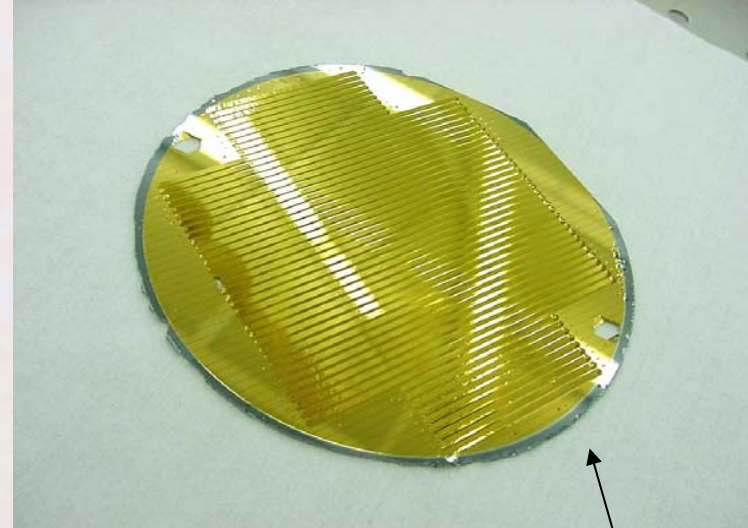
- **NO COPPER**
  - Eliminates corrosion failures
  - Simple filtered water requirements for stack cooling
  - Silicon has better CTE-match for potentially improved “on-off” reliability
- **Monolithic design and low “smile” allows simplifies lensing**
  - Lens arrays using self-aligned silicon “rails”
- **Compact Footprint allows tiling of arrays**
- **Silicon-based technology should enable large scale manufacturability**
  - Lower cost



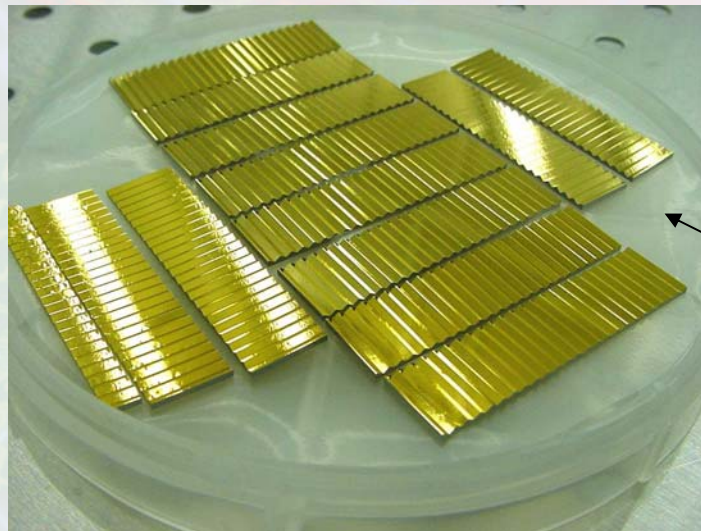
# Silicon “Submount” Fabrication – Vbasis



Post KOH  
etching



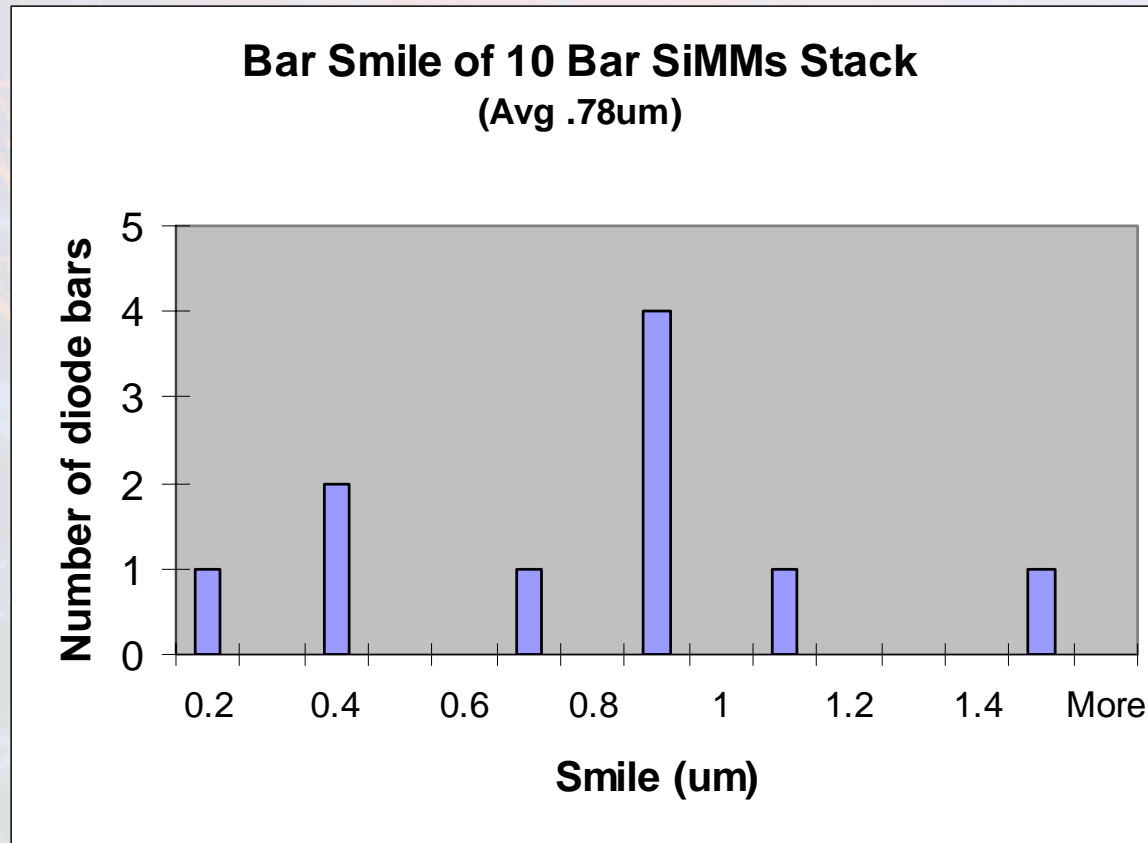
Post  
Metalization



Post Dicing



# SiMMs Characterization - Bar Smile



- Suggests low mounting stress
- Enables easier lensing and beam shaping

Customer	Any				
SO #					
Part Number					
Serial Number	S325-10				
Date	4/25/2006				

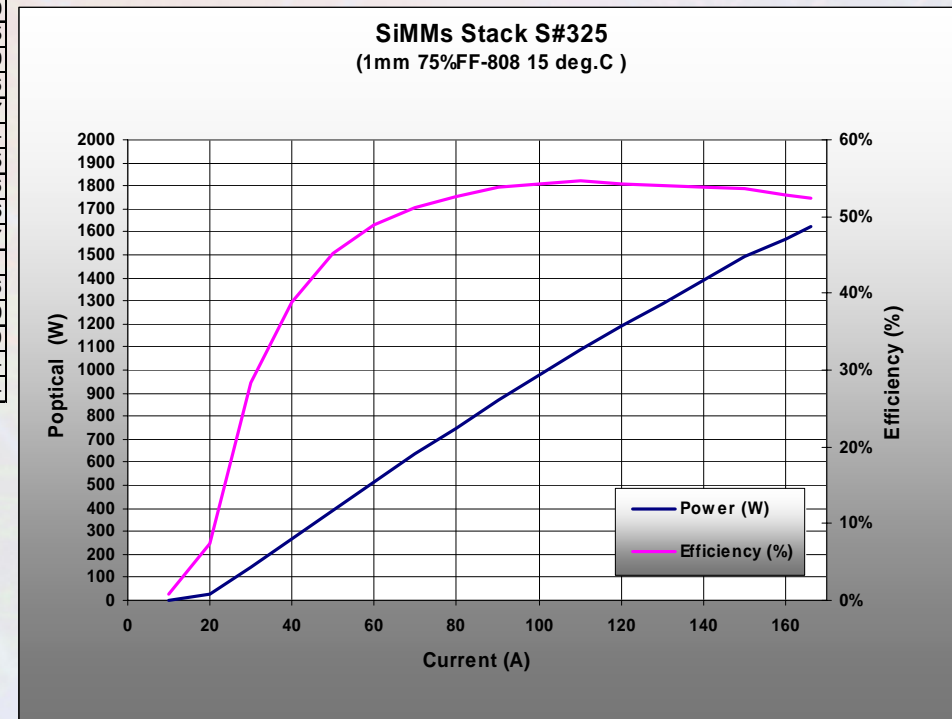


P @ I <sub>max</sub> (W)	1620
I <sub>max</sub>	166
V @ I <sub>max</sub> (V)	18.64
Max Efficiency (%)	55
Temperature (°C)	15
Lamda @ I <sub>max</sub> (nm)	816.64
Pressure Drop (PSI)	38
Flow Rate (LPM)	2

Current (A)	Voltage (V)	Power (W)	Efficiency (%)	Ctr. Wavelength (nm)	Est. T <sub>j</sub>	Pheat
10	16.42	1.5	1%			163
20	16.75	25	7%			310
30	17.00	145	28%			365
40	17.21	268	39%			420
50	17.38	393	45%	808.24	29.9	476
60	17.54	515	49%			537
70	17.68	634	51%	809.49	34.8	604
80	17.81	750	53%			675
90	17.93	868	54%	810.66	39.3	746
100	18.04	978	54%			826
110	18.15	1090	55%	811.99	44.5	907
120	18.26	1190	54%			1001
130	18.35	1290	54%	813.49	50.4	1096
140	18.43	1390	54%			1190
150	18.53	1490	54%	815.31	57.5	1290
160	18.59	1570	53%	816.22	61.0	1404
166	18.64	1620	52%	816.64	62.6	1474

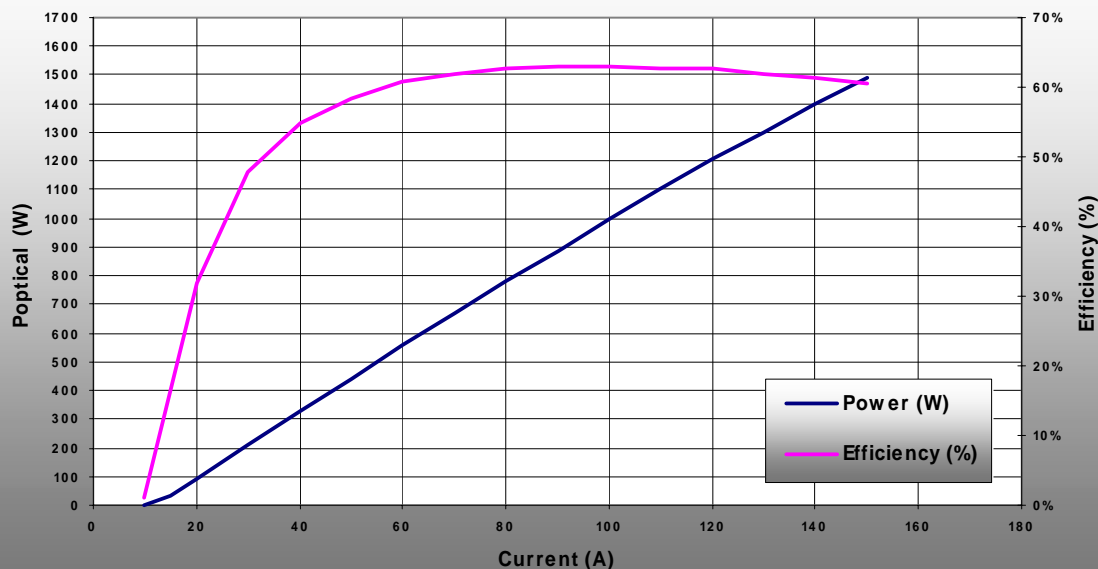
# 808nm SiMMs Stack 15°C

**P<sub>max</sub> = 1620 Watts CW**  
**Max Efficiency = 54%**



# 940 nm SiMMs Stack

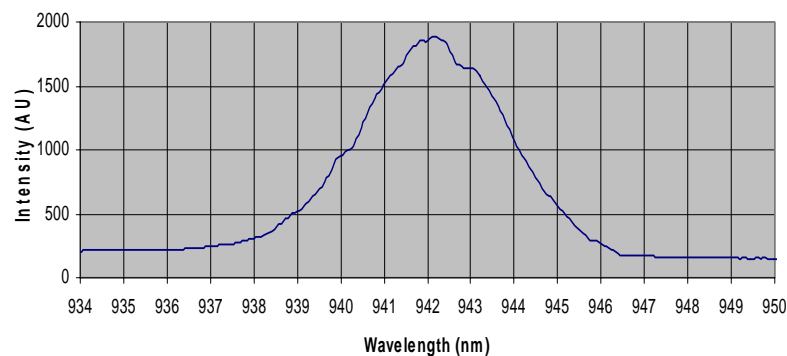
SiMMs Stack S#328  
(1mm 75%FF-940)



**$P_{\max} = 1500\text{W CW}$**   
**Max. Eff. = 63%**

Customer	Hailong Z.	
SO #		
Part Number		
Serial Number	328-SS-10	
Date	5/3/2006	
P @ I <sub>max</sub>	(W)	1490
I <sub>max</sub>	(A)	150
V at I <sub>max</sub>	(V)	16.39
Max Efficiency	(%)	63
Temperature	(°C)	15
Wavelength	(nm)	942.11
FWHM	(nm)	3.93
Pressure Drop	(PSI)	33
Flow Rate	(LPM)	2

CW Spectrum  
(S328 @ 150 15C)





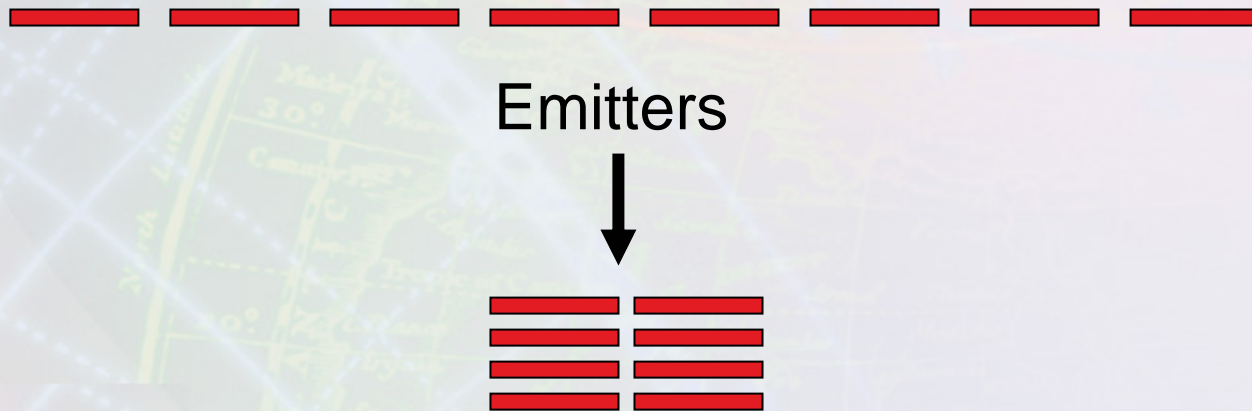
# On The Horizon



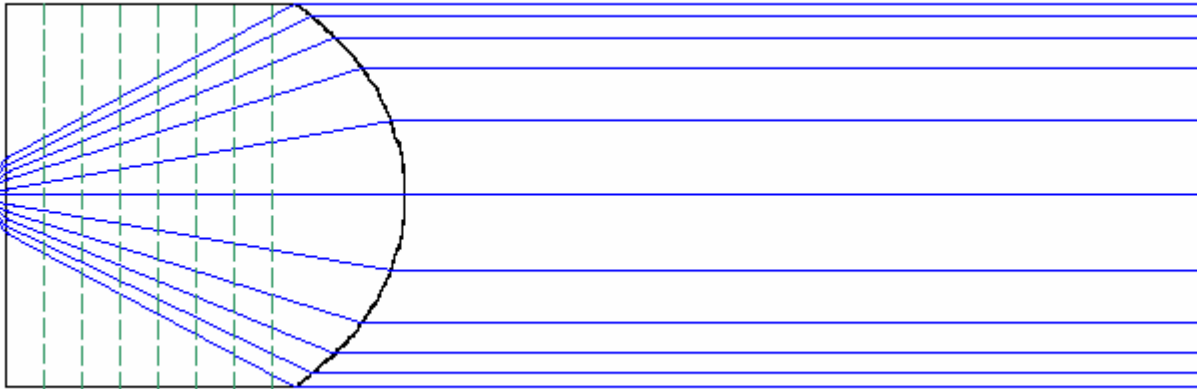


## On The Horizon

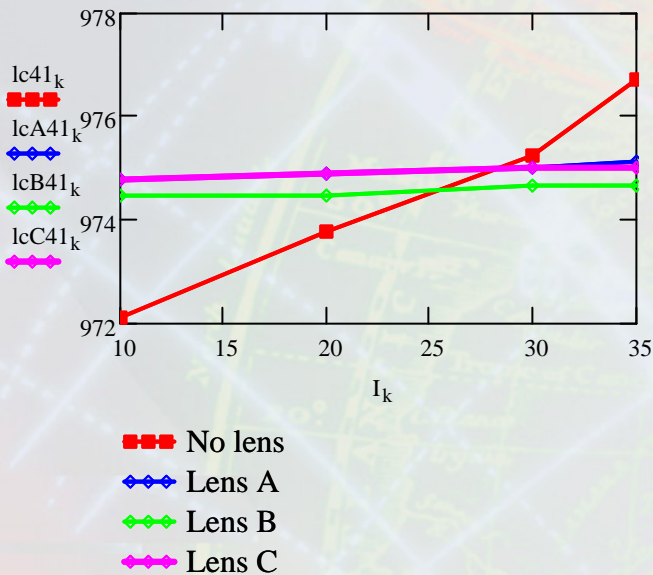
- Further Applications of “Telecom” techniques
  - “Hard Solder” SiMMs
  - No “indium” G-stacks
- Beam Combining to Increase Brightness
  - Spatial Beam Stacking (Out of a Fiber)



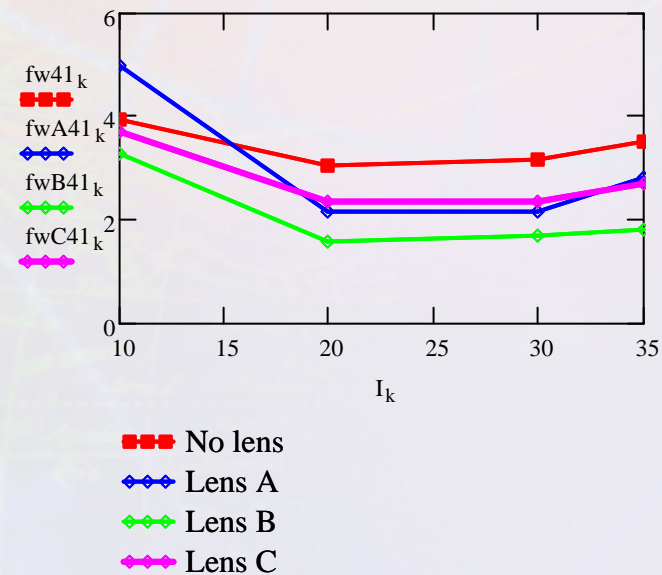
# On the Horizon- Volume Bragg Grating Lens



lin centr, s/n=...41; lenses A,B,C

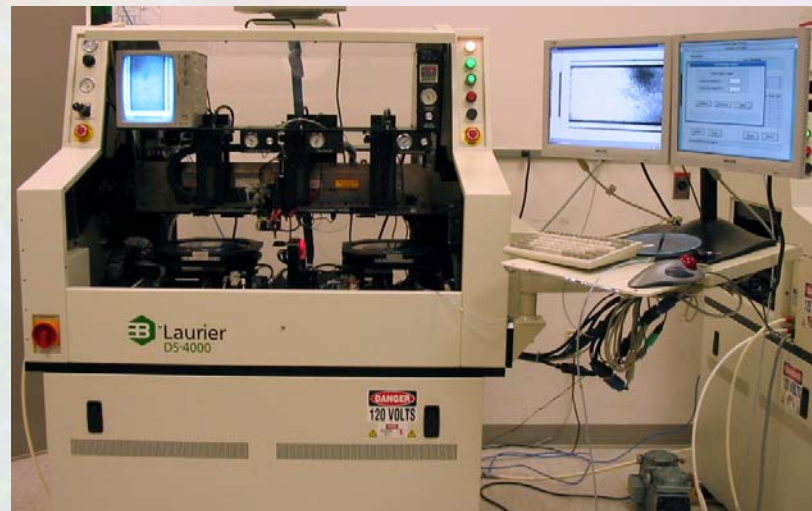


fw90%P, s/n=...41; lenses A,B,C



# On The Horizon – Greater Manufacturing Efficiency

- Driven by Mantech program
- Larger wafers to reduce cost – up to 4" wafers
- Automation of bar inspection to reduce cost
- Automation of stacking/unstacking to increase yield and reduce cost





*Thank You*